

MEMS Probing Solutions

- Manual, Semiautomatic & Fully Automatic Versions
 - Single-Sided or Double-Sided
 - Vacuum (semi and fully automatic)
- Sensors, Accelerometers, Gyroscopes, Microbolometers, Silicon Photonics (DC, HF), Microfluidics
- Thermal Systems from -60 C to 300 C
- In-Plane and Out-of-Plane Measurements
- Customized Chucks and Carrier Plates
- Integrating Spheres or Fibers (single or multi-mode)
- Manipulators – manual, programmable and hexapods
- Non-Contact Height Measurement Sensors
- Probe Tips, Probe Cards, Wedges
- Integrated Solutions
- Modular PS4L Hardware & Software Architecture

